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Sheet	1	of	1	Attorney Docket Number	029437-0108			

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.1	U.S. Patent Document			Date of Publication of	Pages, Columns, Lines, Where Relevant
		Number	Kind Code ² (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Passages or Relevant Figures Appear
	A1	2002-0005528	A1	Masaki NAGAHARA	01/17/2002	
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Examiner Initials*	Cite No.1	Offic	Foreign Patent Do e ³ Number ⁴	ocument Kind Code ⁵ (if known)	Name of Patentee or Applicant of Cited Documents	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ₆
	A2	JP	09-307097	Α	Sony Corp.	11/28/1997		Α
	A3	JP	2000-100831	Α	NEC Corp.	04/07/2000		Α
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	A7	ANDO et al., "A 110-W AlGaN/GaN Heterojunction FET on Thinned Sapphire Substrate," IEDM 01, 2001, pp. 381-384.				
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